

Field Emission Scanning Electron Microscope

COMPLETE THIS FORM TO INITIATE SUPPLIER SCOUTING MEPNN Supplier Scouting Opportunity Synopsis

*The submitting entity agrees to notify NIST MEP of the status of actions taken as a result of this scouting instance within 30 days after receiving a results report. For instances where the submitting entity is an MEP Center submitting on behalf of a client, the MEP Center agrees to notify NIST MEP on behalf of their client. For instances where the submission is direct from federal/state agencies or is a private company, the submitting federal/state agency or private company entity agrees to notify NIST MEP. Notification should be via email to scouting@nist.gov, indicating the following:

- Contact with matches identified in report complete and supply contract awarded, process complete
- Contact with matches identified in report complete and no supply contract awarded, process complete
- Contact with matches identified in report complete and supply negotiations underway, process in progress
- Contact with matches identified in report underway; supply negotiations not yet begun; process in progress

30

Opportunities will be posted for 30 days unless specified

_davs

- Contact with matches identified in report not yet begun, process in progress
- Contact with matches identified in report will not occur within the next 6-months, process complete

ltem to	be Scoute	d
Please o	lescribe tl	he item application/ the end use of item.* Provide the item number if applicable: (N95 Mask vs Protective Mask).
the Cente governme nanofabrie	r for Nanosca nt agencies i cation. This m	of Standards and Technology (NIST) seeks information on commercial vendors that are capable of providing a Field Emission Scanning Electron Microscope (FESEM) to support nanofabrication in ale Science and Technology (CNST), NIST's NanoFab user facility. The FESEM will be sited and used as a shared resource accessible to researchers from industry, academia, NIST, and other n the CNST NanoFab. CNST seeks a high resolution FESEM to provide fundamental multi-scale morphological and physical information for tracking wafer processing parameters during nicroscope will replace existing SEM imaging capability in the CNST NanoFab for imaging materials on the nanometer and micrometer scale during nanofabrication. The system must be capable of of nonconductive samples, including photoresist-coated wafers and quartz wafers.
2022 Supplier		; Number (NIST MEP use)
3345	16	
Scouting	g custome	er/product NAICS Code, if known
TECHNICAL INFORMATION:	<u>-</u>	a. Type of supplier being sought*
	Supplier	Manufacturer Ontract Manufacturer Distributor
		Other
		b. Reason for scouting submission*
IFO	Information	□ 2 nd Supplier □ Price □ Re-shore □ Past supplier no longer available
RM.	natio	New Product Startup
AT	on	Other
NO NO		
	a N	a. Describe the manufacturing processes (elaborate to provide as much detail as possible).*
	е <u>-</u>	Item needed as one standalone unit b. Provide dimensions / size / tolerances / performance specifications for the item.* his FESEM is intended to be used by NanoFab users who need to quickly perform inspection of wafers during nanofabrication. The FESEM must have excellent low voltage performance for imaging nonconductive samples and have the ability to image wafers up to 100 mm (4 inch) in diameter. The microscope shall have an extremely stable gun that is capable of operating 24 hours a day, 7 days a week. 2. BASE MICROSCOPE a. The microscope shall have a minimum resolution of 0.5 nm at 15 kV and <1.0 nm at 1 kV. b. The microscope shall be capable of operating with probe currents between
	Specific ements:	1 pA (or less) and 20 nA (or greater). c. The microscope shall be equipped with a minimum of 3 electron detectors, an Everhart Thornley secondary detector, and in-lens secondary and backscatter electron detectors. d. The microscope shall be equipped with a five axis stage. e. The microscope chamber shall be able to accommodate up to a 100 mm (4 inch) diameter wafer with travel of at least 130 mm and 130 mm in the x and y directions respectively, z travel of 50 mm, tilt of -4 to 70 degrees, and rotation of 360 degrees. f. The microscope shall be equipped with load lock for specimen exchange. g. The microscope shall be equipped with navigation camera.



c. List required materials needed to make the product, including materials of product components.*

Item needed as one standalone unit



		d. Are there applicable certification requirements?*
		e. Are there applicable regulations?* 🗆 Yes 🛛 🔳 No
		Please explain
	-	
	cont:	e. Are there applicable regulations?* Yes No Please explain Image: Section of the standards, requirements, etc.?* Yes No f. Are there any other standards, requirements, etc.?* Yes No
		Please explain
		g. Additional Comments: Is there other information that would impact the item's performance or usefulness? Please explain.
		usefulness? Please explain.
	-	
BU	3. Volume a Pricing	ω 3a. Estimated potential business volume (i.e., # Units Per Day, Month, Year) *:
SINE	cing	One Unit
SS IN		
FORN		b. Estimated target price / unit cost information (flexible and negotiable <u>not</u> accepted) *:
BUSINESS INFORMATION:		\$700,000.00 a. When is it needed by? (Immediate, 30 Days, 6 months, etc.)*
		b. Describe packaging requirements (i.e., individually/group packaging)*
		ASAP b. Describe packaging requirements (i.e., individually/group packaging)* Flexible c. Where will this item be shipped?* NIST, 100 Bureau Drive, Gaithersburg, MD 20899
		c. Where will this item be shipped?*
		MIST, 100 Bureau Drive, Gaithersburg, MD 20899
-		,
		ဟာ Is there other information you would like to include?
		Additional Comments: